## Notice of References Cited Application/Control No. 10/519,599 Examiner David Y. Chung Applicant(s)/Patent Under Reexamination LEE ET AL. Page 1 of 1

## **U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	Α	US-6,636,282	10-2003	Ogawa et al.	349/58
*	В	US-7,178,963	02-2007	Ueda et al.	362/615
*	С	US-6,958,789	10-2005	Cueff et al.	349/61
*	D	US-2002/0113924	08-2002	Saito et al.	349/112
*	Е	US-6,407,781	06-2002	Kitada, Takaaki	349/58
	F	US-			
	G	US-			
	Н	US-			
	1	US-			
	J	US-			
	K	US-			
	L	US-			
	М	US-			

## **FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	Ν					
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	R					
	S					
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## **NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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